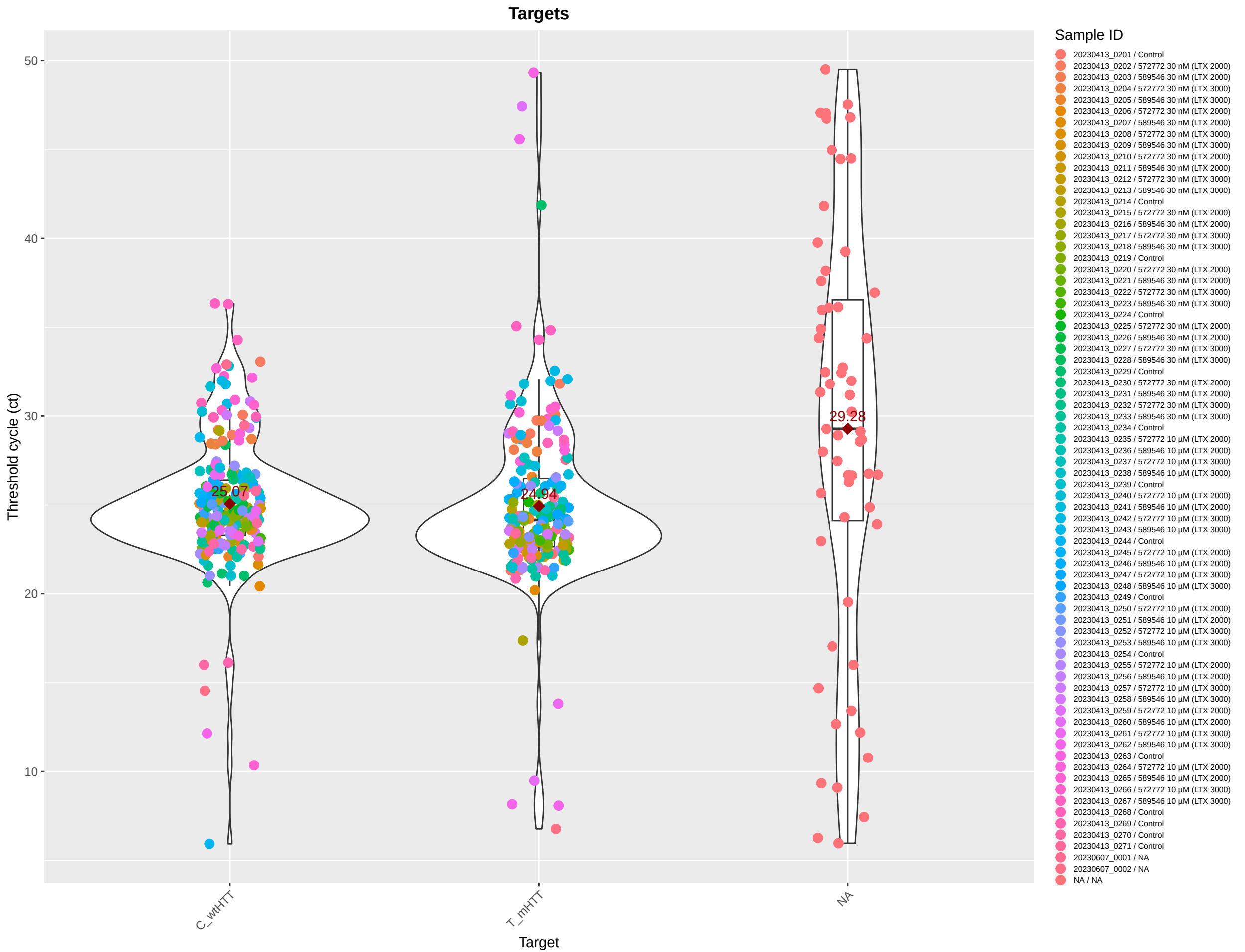
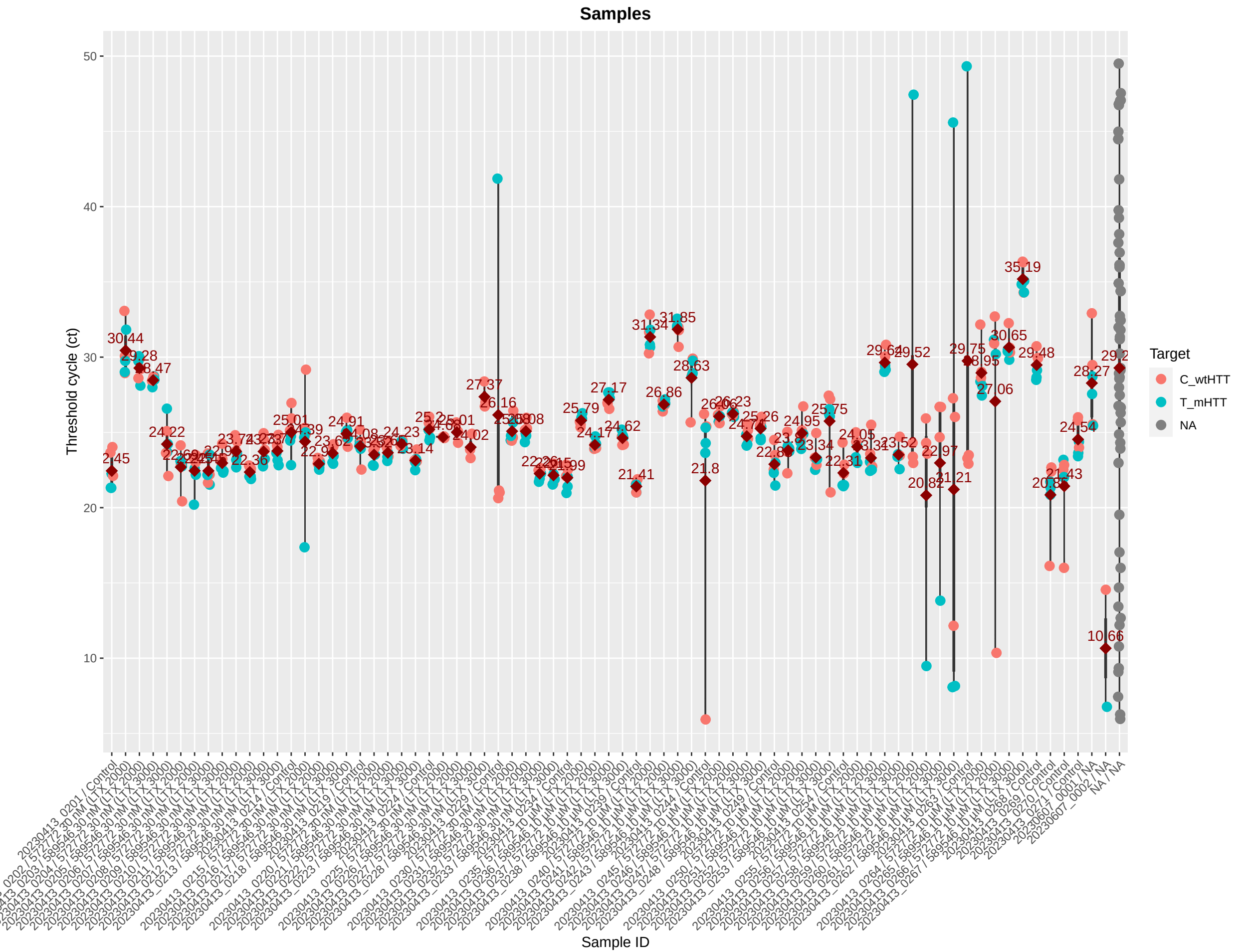
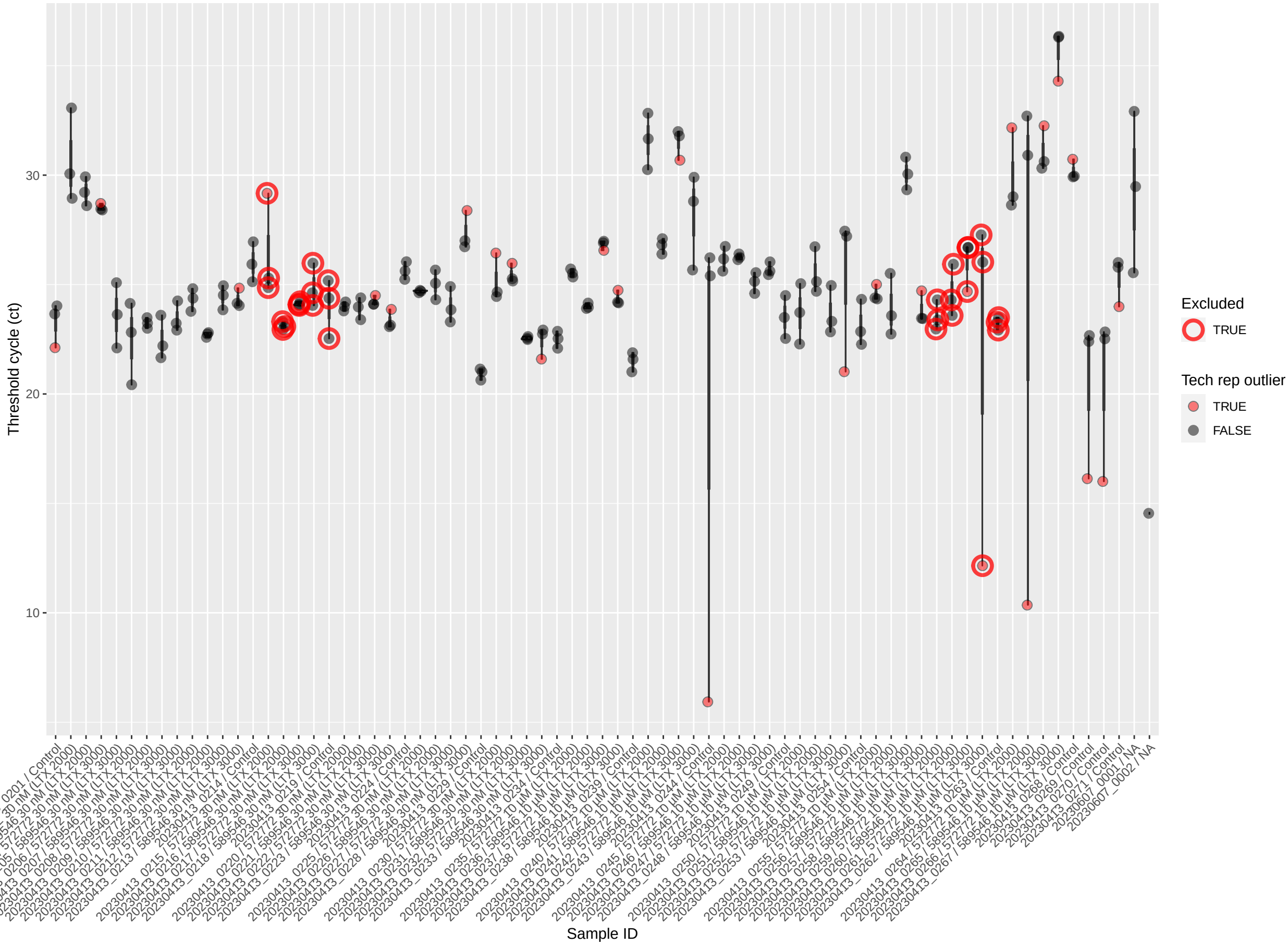

Targets
Threshold cycle (ct)
50
40
30
20
10
25.07
24.94
29.28
C_wtHTT
T_mHTT
NA
Target
Sample ID
20230413_0201 / Control
20230413_0202 / 572772 30 nM (LTX 2000)
20230413_0203 / 589546 30 nM (LTX 2000)
20230413_0204 / 572772 30 nM (LTX 3000)
20230413_0205 / 589546 30 nM (LTX 3000)
20230413_0206 / 572772 30 nM (LTX 2000)
20230413_0207 / 589546 30 nM (LTX 2000)
20230413_0208 / 572772 30 nM (LTX 3000)
20230413_0209 / 589546 30 nM (LTX 3000)
20230413_0210 / 572772 30 nM (LTX 2000)
20230413_0211 / 589546 30 nM (LTX 2000)
20230413_0212 / 572772 30 nM (LTX 3000)
20230413_0213 / 589546 30 nM (LTX 3000)
20230413_0214 / Control
20230413_0215 / 572772 30 nM (LTX 2000)
20230413_0216 / 589546 30 nM (LTX 2000)
20230413_0217 / 572772 30 nM (LTX 3000)
20230413_0218 / 589546 30 nM (LTX 3000)
20230413_0219 / Control
20230413_0220 / 572772 30 nM (LTX 2000)
20230413_0221 / 589546 30 nM (LTX 2000)
20230413_0222 / 572772 30 nM (LTX 3000)
20230413_0223 / 589546 30 nM (LTX 3000)
20230413_0224 / Control
20230413_0225 / 572772 30 nM (LTX 2000)
20230413_0226 / 589546 30 nM (LTX 2000)
20230413_0227 / 572772 30 nM (LTX 3000)
20230413_0228 / 589546 30 nM (LTX 3000)
20230413_0229 / Control
20230413_0230 / 572772 30 nM (LTX 2000)
20230413_0231 / 589546 30 nM (LTX 2000)
20230413_0232 / 572772 30 nM (LTX 3000)
20230413_0233 / 589546 30 nM (LTX 3000)
20230413_0234 / Control
20230413_0235 / 572772 10 µM (LTX 2000)
20230413_0236 / 589546 10 µM (LTX 2000)
20230413_0237 / 572772 10 µM (LTX 3000)
20230413_0238 / 589546 10 µM (LTX 3000)
20230413_0239 / Control
20230413_0240 / 572772 10 µM (LTX 2000)
20230413_0241 / 589546 10 µM (LTX 2000)
20230413_0242 / 572772 10 µM (LTX 3000)
20230413_0243 / 589546 10 µM (LTX 3000)
20230413_0244 / Control
20230413_0245 / 572772 10 µM (LTX 2000)
20230413_0246 / 589546 10 µM (LTX 2000)
20230413_0247 / 572772 10 µM (LTX 3000)
20230413_0248 / 589546 10 µM (LTX 3000)
20230413_0249 / Control
20230413_0250 / 572772 10 µM (LTX 2000)
20230413_0251 / 589546 10 µM (LTX 2000)
20230413_0252 / 572772 10 µM (LTX 3000)
20230413_0253 / 589546 10 µM (LTX 3000)
20230413_0254 / Control
20230413_0255 / 572772 10 µM (LTX 2000)
20230413_0256 / 589546 10 µM (LTX 2000)
20230413_0257 / 572772 10 µM (LTX 3000)
20230413_0258 / 589546 10 µM (LTX 3000)
20230413_0259 / 572772 10 µM (LTX 2000)
20230413_0260 / 589546 10 µM (LTX 2000)
20230413_0261 / 572772 10 µM (LTX 3000)
20230413_0262 / 589546 10 µM (LTX 3000)
20230413_0263 / Control
20230413_0264 / 572772 10 µM (LTX 2000)
20230413_0265 / 589546 10 µM (LTX 2000)
20230413_0266 / 572772 10 µM (LTX 3000)
20230413_0267 / 589546 10 µM (LTX 3000)
20230413_0268 / Control
20230413_0269 / Control
20230413_0270 / Control
20230413_0271 / Control
20230607_0001 / NA
20230607_0002 / NA
NA / NA


Samples
Threshold cycle (ct)
50
40
30
20
10
Target
C_wtHTT
T_mHTT
NA
Sample ID

Outliers and exclusions

C_wtHTT



Outliers and exclusions

T_mHTT

Threshold cycle (ct)

50
40
30
20
10

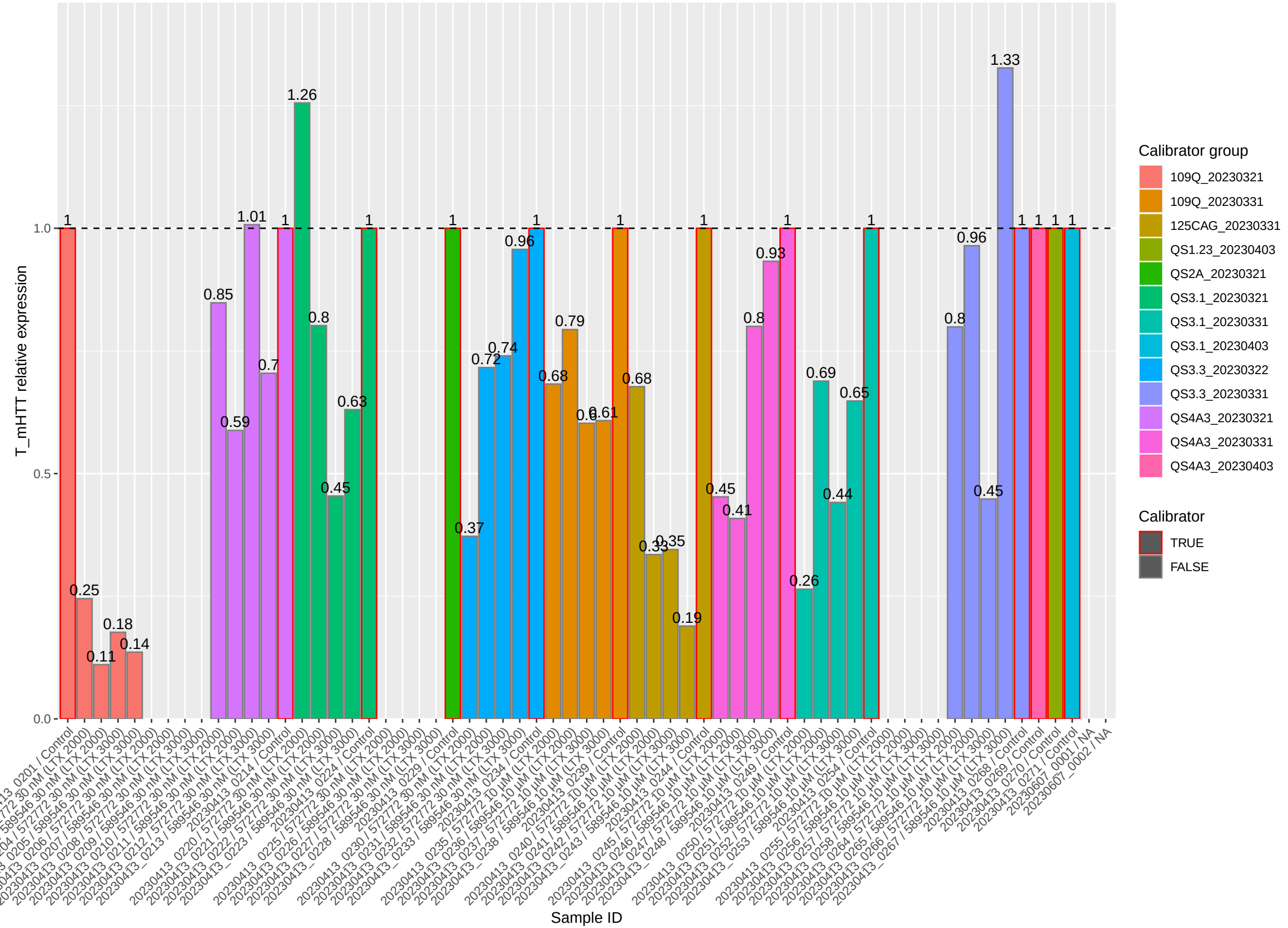
Excluded
TRUE

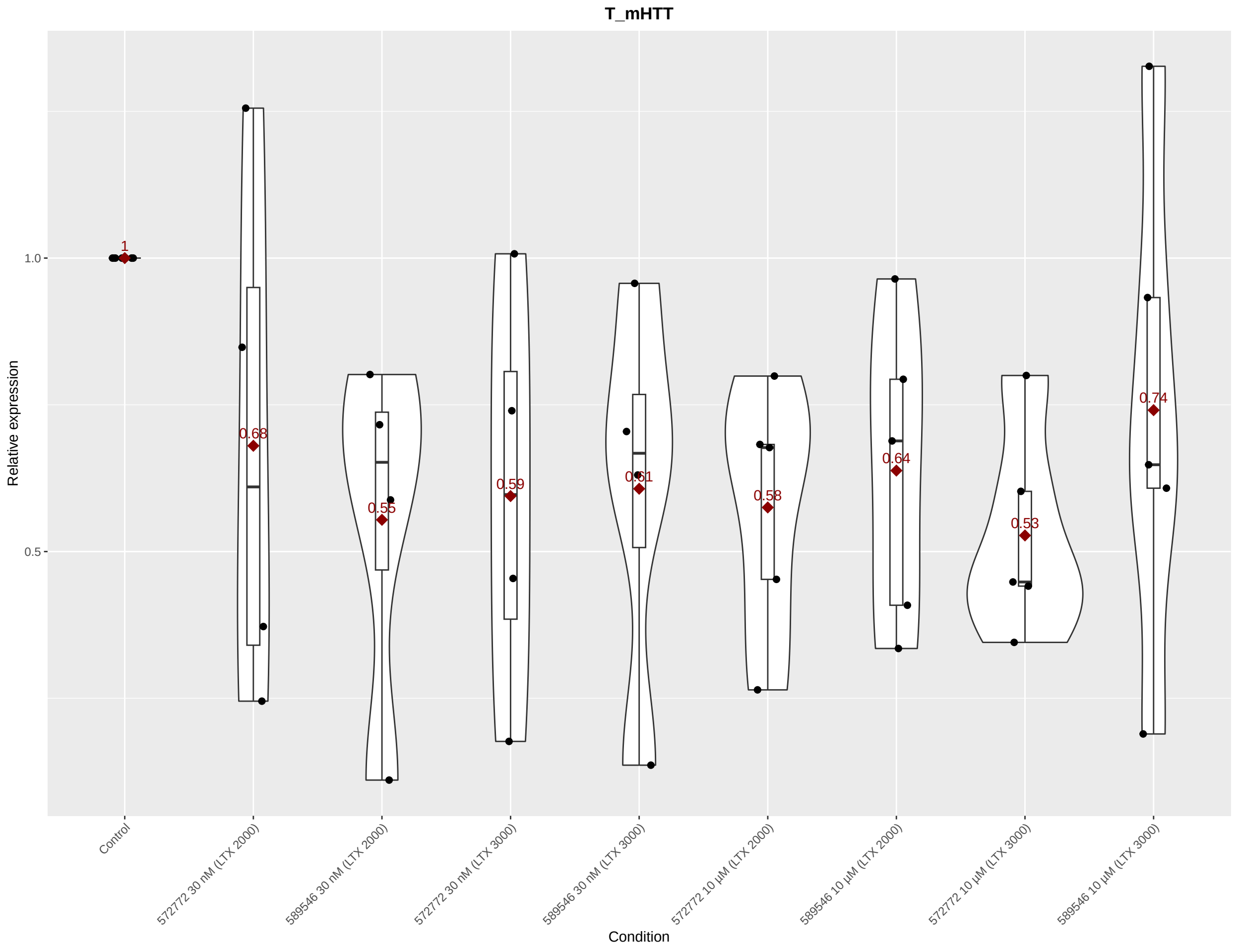
Tech rep outlier
TRUE
FALSE

Sample ID

Relative expression

T_mHTT




T_mHTT
Relative expression
1.0
0.5
1
0.68
0.55
0.59
0.61
0.58
0.64
0.53
0.74
Control
572772 30 nM (LTX 2000)
589546 30 nM (LTX 2000)
572772 30 nM (LTX 3000)
589546 30 nM (LTX 3000)
572772 10 µM (LTX 2000)
589546 10 µM (LTX 2000)
572772 10 µM (LTX 3000)
589546 10 µM (LTX 3000)
Condition